

PATENT ABSTRACTS OF JAPAN

(11)Publication number : 2002-050572

(43)Date of publication of application : 15.02.2002

(51)Int.Cl.

H01L 21/027
G01B 11/00
G01B 11/24
G01B 15/00

(21)Application number : 2001-145171

(71)Applicant : JEOL LTD

(22)Date of filing : 15.05.2001

(72)Inventor : NORIOKA SETSUO
SAITO MANABU
TOYAMA AKIRA

(30)Priority

Priority number : 2000146348 Priority date : 18.05.2000 Priority country : JP

(54) PATTERN CONNECTION ACCURACY INSPECTING METHOD

(57)Abstract:

PROBLEM TO BE SOLVED: To realize a pattern connection accuracy inspecting method which inspects with high accuracy and at a high speed, the connection accuracy at region boundaries of a pattern exposed or written on many regions by each region.

SOLUTION: An image memory 44 stores secondary electronic signals detected by scanning a charged particles beam over each of inspecting regions as inspection images, together with their position coordinates. After fetching of the images of all inspecting regions, an image processor 45 compares the inspecting images with separately prepared reference images to extract corresponding patterns at the inspecting regions to the reference images, thereby detecting the deviation of field connections, etc., from relative positions of these patterns.

